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# Methane oxidative conversion pathways in a dielectric barrier discharge reactor—Investigation of gas phase mechanism

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#### **Abstract**

Non-thermal plasma, over the past few years, is being investigated for methane conversion. In order to improve the efficiency, combined plasma and catalyst is being explored to exploit possible synergetic effects. The present paper investigates plasma assisted methane conversion in gas phase by partial oxidation at low energy density (80–200 kJ/mol CH4) and low reactor temperatures (130–140 ◦C). Although non-thermal plasma has the inherent advantage of initiating reactions, a disadvantage is the unfavorable selectivity to the desired product. The investigation attempts to identify the plasma initiated chemical reaction pathways by combining experiments and kinetic modeling. Sensitivity analysis indicates reaction intermediates leading to formation of oxygenates as an alternative oxidation pathway at the investigated temperatures (*T* < 200 ◦C). The selectivity for synthesis gas formation could be increased by partial oxidation at higher CH<sub>4</sub>/O<sub>2</sub> ratios. Combined partial oxidation and steam reforming was as well investigated in order to increase H<sub>2</sub> concentration. Isotopes were used in order to identify reaction pathways for the case of steam reforming experiments. However, experiments at lower energy density indicate negligible steam conversion. At lower temperatures, the input plasma energy is primarily used for  $CH<sub>4</sub>/O<sub>2</sub>$  conversion.

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## **1. Introduction**

Methane steam reforming is commercially used as a viable process for synthesis gas production. However, partial oxidation has always been a desired process due to its exothermic nature. But in order to exploit oxidative conversion, the following technical problems need to be overcome [\[1\]:](#page-10-0)

- (a) High temperatures (>800 K) are needed for activation of methane molecule. This calls for very stable materials, if a catalytic reactor is used (which is often done for the sake of selectivity).
- (b) At these extreme conditions, carbon formation reactions are favored (973 K  $\lt$  *T*  $\lt$  1273 K), which leads to coke deposition and blockage of active sites coupled with plugging of the reactor, hindering regular operation.

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Non-thermal plasma, due to its ability to create reactive species, can be an alternative method for excitation of methane molecule, either by direct electron impact dissociation or by indirect radical reactions. This principle has been used for removal of compounds (pollution control) with varying degree of success. Investigations into processes such as plasma induced NOx and SOx removal, VOC removal from air or air like mixtures, at room temperature to 100 ◦C, have indicated the removal mechanism to be initiated by formation of O species [\[2\].](#page-10-0) Likewise, studies focusing on the removal of polyaromatic hydrocarbons from fuel gas mixtures, at temperature ranging from 200 to 500  $\degree$ C, have indicated primary mechanism to be CO<sub>2</sub> dissociation [\[3,4\]. T](#page-10-0)hus, due to its inherent ability to create reactive species, non-thermal plasma can be utilized to initiate or sustain reactions at lower operating temperatures. Similar approach is intended for  $C_1$  partial oxidation process. In this context, various reactor configurations have been studied for this application. A point to plate configuration with a con-current flow in an ac discharge reactor has indicated CH4 conversion in the range of 10–20% for a  $CH<sub>4</sub>/O<sub>2</sub>$  ratio of 3–5 at energy consumption of 10 eV/(molecule of CH<sub>4</sub>) (960 kJ/mol of CH<sub>4</sub>) [\[5\].](#page-10-0) The H<sub>2</sub>/CO ratio was reported to be in the range of 2–3, with a selectivity of

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 $20-30\%$  for  $C_2$  products at room temperature. Combined plasma catalyst reactor can be an alternative pathway to improve selectivity. However, in order to choose an appropriate catalyst or design a catalyst, essential information is the knowledge of gas phase reaction, especially for the case of non-thermal plasma induced processes. For the case of plasma catalytic CH<sub>4</sub> partial oxidation process, dielectric barrier discharge (DBD) reactors have been used in the temperature range from 200 to 400 $\degree$ C at energy density in the order of 800–1000 kJ/mol CH $_4$  [\[6\]. R](#page-10-0)esults reported over  $\alpha$ -Al<sub>2</sub>O<sub>3</sub> as a bed material indicate H<sub>2</sub> selectivity to be in the order of 20–30% at the temperatures investigated. In presence of a commercial  $Ni/\gamma Al_2O_3$  catalyst, the H<sub>2</sub> selectivity was higher (60%) at temperatures higher than 400  $\degree$ C.

In spite of such investigations, there is still a lack of information about the basic chemical mechanisms, since the main focus is on increasing CH4 conversion. A consequence of the ongoing "plasma CH4 conversion race" is the high energy used in the experiments. This results in conversion of input electrical energy into thermal heat or joule heating. The observed conversion is then a result of thermal process, masking the plasma process. From energy efficiency point of view, non-thermal plasma induced radical initiated process would be beneficial than utilizing non-thermal plasma as a heat source. The present investigation thus attempts to study methane conversion at low energy levels in DBD reactors to elucidate the chemical reaction pathways. Low temperatures are used to focus on plasma process. As a first step, only gas phase processing is investigated. Combined partial oxidation and steam reforming is studied as an alternative way to increase  $H_2$  production by dissociation of water molecules or by induced radical dissociation process. To summarize, we attempt to focus on:

- (a) reaction pathways for product formation from plasma assisted partial oxidation process;
- (b) reactions influencing desired product formation;
- (c) influence of non-thermal plasma for the case of combined steam and partial oxidation process.

#### **2. Experimental set-up**

The experiments are carried out in a DBD reactor (glass tube) with an inner diameter of 1 cm and length of 7 cm, thus a total reactor volume of  $5.5 \text{ cm}^3$ . The high voltage electrode consists of SS-304 rod with a diameter of 0.1 cm, energized by a high voltage amplifier (TREK). A steel foil wrapped around the tube serves as a ground electrode. The entire set-up was placed inside an oven to have uniform temperature ( $T = 130$ °C). CH<sub>4</sub> and O<sub>2</sub> were the principle reactants for the experiments, fed at varying ratios. In order to establish mass balance, CH<sub>4</sub> was fed with 10%  $N_2$ . The reactor was energized by an ac high voltage  $12-13$  kV at a frequency of 250 Hz, with a power equivalent of 3 W. The input power was limited to these values so as not to increase temperature of the packed bed by way of plasma heating. At a power input of 3 W, the resulting temperature increase at the outer electrode was in the order of 10 ◦C. Thus, on account of low energy density, methane conversions were low (1–2%). The product composition was measured by a GC equipped with a



Fig. 1. Experimental set-up.

thermal conductivity detector (TCD)  $(H_2, CH_4$  measurements), and a FID (for CO and hydrocarbon measurements) (Fig. 1).

For the case of combined partial oxidation and steam reforming, D2O (heavy water) was used to track steam conversion. Steam was injected into the reactor by means of a constant feeding pump at a rate of 4 ml/h. A QMS (quadrapole mass spectrometer, Balzers) was used to distinguish the species  $H<sub>2</sub>$ ,  $HD, D<sub>2</sub>$  formed during the conversion process. Product composition is reported in terms of the moles of product formed per mole of CH4 converted.

Product selectivity = moles of product formed/moles of C detected at the output.

#### **3. Results**

#### *3.1. Experimental investigation*

Plasma assisted partial oxidation was performed in gas phase as well as different bed materials in order to investigate the effect of packing material in the discharge.  $\alpha$ -Al<sub>2</sub>O<sub>3</sub> and Ni/ $\gamma$ -Al<sub>2</sub>O<sub>3</sub> was used as a bed material/catalyst in order to simultaneously investigate the effect of a catalyst. Experiments were carried out at CH<sub>4</sub>/O<sub>2</sub> ratio of 2 (CH<sub>4</sub> = 44 sccm, O<sub>2</sub> = 21 sccm) at temperatures of 130 °C (electrode temperature =  $138$  °C) and energy density of  $80-100 \text{ kJ/mol}$  CH<sub>4</sub> (total energy =  $800 \text{ J/l}$ (total gas flow rate)). [Fig. 2\(a](#page-2-0)) indicates the product selectivity observed over different packing materials. In all the cases, the observed selectivity for  $C_2$  production was rather low  $\left(\frac{2\%}{2}\right)$ .  $H_2$  selectivity is in the order of 30 %, while CO/CO<sub>2</sub> ratio is about 2.

 $\alpha$ -Al<sub>2</sub>O<sub>3</sub>, by itself, does not exhibit any catalytic activity at the experimental conditions ( $T = 130-150$ °C) for methane conversion. Furthermore, in presence of plasma, it has been reported that the observed conversion is same as the case for an empty DBD [\[6\],](#page-10-0) which was also seen in our experiments as well. The observed product distribution remained largely unchanged even at higher energy densities for the case of gas phase process. At higher temperatures ( $T > 300-400$ °C), the nature of bed material seems to have an influence on the product composition [\[6\].](#page-10-0) In order to determine, if the  $H<sub>2</sub>$  oxidation reaction is a surface

<span id="page-2-0"></span>

Fig. 2. (a) Experiments over different bed materials and (b) experiments at different  $CH<sub>4</sub>/O<sub>2</sub>$  ratio.

reaction or a gas phase reaction at the investigated temperatures, conversion over  $Ni/\gamma$ -Al<sub>2</sub>O<sub>3</sub> was studied. It is known that Ni has a high reforming activity and therefore we can expect higher H<sub>2</sub> production if surface reaction do play a role. However, the activation temperature for such a catalyst composition is high  $(>400\degree C)$ , hence no significant difference in reaction pathways is observed. Nevertheless, a DBD discharge with the present configuration does not seem to change/affect the activity of a catalyst. Further, as can be seen from experimental results, the catalytic surfaces do not participate in the reaction pathway. This may be because of the low temperatures (less than the temperature needed for the activation of the catalytic surface, such as Ni) used for the experimental study. In other words, at the experimental conditions, the product distribution is only influenced by plasma initiated process. Fig. 2(b) indicates the product distribution as observed for the case of partial oxidation in lean  $O_2$  mixture (CH<sub>4</sub>/O<sub>2</sub> = 24). Apart from the indicated product distribution,  $C_3$  formation was as well observed. From the results in Fig. 2, it can be observed that the  $H<sub>2</sub>/CO$  formation seems to be limited by its relative oxidation rates. A logical interpretation would be the limitation imposed by the competitive reaction rates for  $H_2$  consumption and formation. In other words, the  $H_2$  selectivity primarily seems to be dictated by the fast  $H_2-O_2$  reaction to form  $H_2O$ . Based on the above analysis, a decrease in O radical concentration would therefore limit the excessive H oxidation and increase selectivity towards  $H_2$ production. Accordingly, experiments at higher  $CH<sub>4</sub>/O<sub>2</sub>$  ratios favored  $H_2$  formation as seen in Fig. 2(b). Thus, controlling gas phase interactions is one possible alternative to increase or change product distribution. Similar observations have been

made other groups that the product distribution from plasma assisted partial oxidation process is primarily a result of gas phase reactions [\[6\].](#page-10-0)

### *3.2. Kinetic modeling*

In order to further study gas phase process and to have more insight into the chemical mechanism, a simple kinetic model has proven to be a useful technique [\[3,4,7–9\].](#page-10-0) Non-thermal plasma chemical process involves active generation of electrons, metastables and ions and their induced chemical reactions. All the physical processes contribute to generation of radicals. To depict an actual process, one needs to have a "perfect" discharge model to describe the distribution of the species produced in both the axial and radial directions. Unfortunately, this is far from reality. Hence, in this paper, a fitting parameter is used to evaluate the amount of radicals necessary for the conversion process as observed experimentally. In the present numerical calculation, radical production is incorporated in the rate constant of the process [\[7\].](#page-10-0) Therefore, both phases in the reactor, viz. the plasma phase as well as the bulk gas phase are well mixed; hence, the model can be termed as a pseudo-homogenous model. Similar approaches have been done in past works by other researchers and useful information related to the discharge chemistry has been obtained [\[3,4,7–9\].](#page-10-0)

The numerical calculation is done with the following assumptions:

- (1) radicals produced are well mixed with reactants;
- (2) radicals once produced are uniformly distributed within the whole volume, i.e. a zero-dimensional model;
- (3) chemistry of the process is solely described by radical behavior;
- (4) initial radical production is directly proportional to the related bulk gas composition;
- (5) thermal decomposition at the conditions of the experiment  $(T=130-200\degree C)$  is negligible.

Similar to decomposition mechanism described elsewhere [\[8,9\], t](#page-10-0)he initial plasma reaction is represented by the following four reactions:



A total of 180 reactions with 29 species are used to describe the plasma assisted CH4 partial oxidation at the conditions of the experiment  $(T = 130-200 \degree C)$  ([Appendix A\).](#page-7-0)

Molecular species:  $H_2$ ,  $O_2$ ,  $H_2O$ ,  $H_2O_2$ ,  $CH_4$ ,  $CO$ ,  $CO_2$ ,  $CH_3OH$ ,  $CH_2O$ ,  $C_2H_2$ ,  $C_2H_4$ ,  $C_2H_6$ ,  $C_3H_8$ .

Radical species: H, O, OH,  $HO_2$ , CH, CH<sub>2</sub>, CH<sub>3</sub>, HCO,  $CH_2OH$ ,  $CH_3O$ ,  $C_2H$ ,  $C_2H_3$ ,  $C_2H_5$ ,  $HCCO$ ,  $C_3H_7$ ,  $CH_2CO$ .

The oxidation scheme represented in the numerical calculation is indicated in [Fig. 3.](#page-3-0) As observed from experimental results,  $C_3$  formation was included in the calculation process. Solid formation reactions, and formation of  $C_2$  and  $C_3$  oxygenates were not considered in the present case as was observed

<span id="page-3-0"></span>

Fig. 3. Reaction scheme for calculation.

in the experiments as well. CO termination to  $CO<sub>2</sub>$  was done by way of radical reactions as well as by additional oxidation pathway which occurs at the wall or in the high temperature zones in the vicinity of a micro discharge. The aim of the calculation is mainly to identify the reaction which can influence the final product selectivity and hence incorporate an appropriate catalytic surface.

The general reaction scheme and the format of the mass conservation equations are:

$$
A \to R; \qquad R + X \to \text{Products}
$$

The initial radical production and its consumption can be expressed as:

$$
\frac{\mathrm{d}[R_i]}{\mathrm{d}t} = G_{\mathrm{R}} \cdot E - \sum_j k_{ij} \cdot [R_i] \cdot [X_j] \tag{1}
$$

and otherwise the mass conservation of the species is expressed as:

$$
\frac{d[X_i]}{dt} = \sum_j k_{ji} \cdot [X_i] \cdot [X_j] \tag{2}
$$

where  $G_R$  is the radical production per Joule per  $m^3$  (mol/(J  $m^3$ )):  $K_R \cdot \lambda_R \cdot [M]$ ,  $K_R$  the dissociation constant (fitting parameter)  $(J^{-1})$ , *M* the bulk gas concentration (mol/m<sup>3</sup>),  $\lambda_R$  the gas volume fraction, *E* the energy (W), *k* the reaction rate constant  $(s^{-1})$ ,  $[X_i]$ ,  $[R_i]$  the species concentration (mol/m<sup>3</sup>) and  $[A]$  is the gas component such as  $H_2$ ,  $CO_2$ ,  $H_2O$ .

According to the above hypothesis, we have the following radical yields:

$$
G_{\text{CH}_3} = \alpha \cdot K_{\text{CH}_4} \cdot \lambda_{\text{CH}_4} \cdot [M];
$$
  
\n
$$
G_{\text{CH}_2} = \beta \cdot K_{\text{CH}_4} \cdot \lambda_{\text{CH}_4} \cdot [M];
$$
  
\n
$$
G_{\text{CH}} = \gamma \cdot K_{\text{CH}_4} \cdot \lambda_{\text{CH}_4} \cdot [M];
$$
  
\n
$$
G_{\text{H}} = (\alpha + 3\gamma)K_{\text{CH}_4} \cdot \lambda_{\text{CH}_4} \cdot [M];
$$
  
\n
$$
G_{\text{H}_2} = \beta \cdot K_{\text{CH}_4} \cdot \lambda_{\text{CH}_4} \cdot [M];
$$
  
\n
$$
G_{\text{O}} = K_{\text{O}_2} \cdot \lambda_{\text{O}_2} \cdot [M]
$$

Eq. (1) presents a mass balance of radicals. The first term on the right hand side indicates the production term and the second term represents the formation or consumption of radicals via reactions. Eq. (2) represents the general scheme for secondary radicals during corona processing. The *G* value or the radical yield can then be evaluated according to:

$$
G'(\text{molecules}/100 \text{ eV}) = 9.649 \text{e} - 6 \cdot G_R \cdot V_R \cdot t_{\text{res}} \tag{3}
$$

where *V* is the volume of reactor  $(m^3)$ ,  $t_{res}$  the residence time in reactor (s) and the conversion factor,  $1 \text{ eV} = 1.6e-19 \text{ J}$ ,  $1 \text{ mol} = 6.023 \text{ e}$ <br> $23 \text{ molecules}$ .

The dissociation constants  $K<sub>CH<sub>4</sub></sub>$  and  $K<sub>O<sub>2</sub></sub>$  are functions of the experimental conditions, viz. temperature, energy input and gas composition [\[10\].](#page-10-0) This can be obtained by numerical data fitting procedure with experimental results as done in other works [\[4,8\]](#page-10-0) for a particular temperature and gas composition. However, the ratio of the dissociated fragments  $(\alpha:\beta:\gamma)$  is a function of the electron energy which is similar for the case of a DBD. In a mixture of  $CH<sub>4</sub>$  and electron attaching gases such as  $CO<sub>2</sub>$ , this ratio was determined to be  $0.0645:0.90:0.032$ (1.0e−3:1.4e−2:5.0e−4) [\[8,9\].](#page-10-0) Thus, in the above equation,  $\alpha = 0.0645$ ,  $\beta = 0.90$ ,  $\nu = 0.032$ .

#### *3.2.1. Estimation of* K*CH*<sup>4</sup>

For a correct estimation of  $K<sub>CH<sub>4</sub></sub>$  based on the present approach and for the present experimental conditions, the following factors need to be considered:

- (a) the influence of joule heating needs to be minimized;
- (b) radical chain reactions resulting from  $O<sub>2</sub>$  needs to be avoided or minimized.

Hence experiments were carried out to obtain CH<sub>4</sub> conversion in low  $O_2$  concentration (CH<sub>4</sub>:N<sub>2</sub>:O<sub>2</sub> = 90:8:2) at temperature of 130  $\degree$ C and power input of 2.5 W. The observed CH<sub>4</sub> conversion was about 1% (0.88%). Data fitting was performed by the method of least squares in order to obtain similar  $CH<sub>4</sub>$  conversion, as observed experimentally. The rate constant or the value of  $K_{\text{CH}_4}$  was calculated to be 8e–4 s<sup>-1</sup> J<sup>-1</sup>.

Similar procedure could not be used for obtaining the rate constant for  $O_2$  dissociation, as in the absence of termination reactions from  $CH_4$ , most of the produced O radicals lead to  $O_3$ formation.

$$
e + O_2 \rightarrow O + O + e; \qquad O_2 + M + e \rightarrow O_3 + M
$$

This mechanism is not relevant in the partial oxidation scheme and therefore not included in the reactions. Hence the dissociation constant for  $O_2$  was obtained from experiments in stoichiometric mixture of  $CH<sub>4</sub>/O<sub>2</sub>$  (2:1).

#### 3.2.2. Estimation of  $K_{O_2}$

Using similar procedure as explained in the preceding section, the value of  $K_{\text{O}_2}$  was obtained to be 3e–3 s<sup>-1</sup> J<sup>-1</sup>. CH<sub>4</sub> conversion of 2.3% was realized at temperature of 130 $\degree$ C with a power input of  $2.5 W$  (about  $81 \text{ kJ/mol CH}_4$ ) in a gas composition of  $CH_4$  and  $O_2$  (2:1). The resulting radical yields, at the

Table 1 Radical yields computed at the experimental conditions

$G_{CH_2}$	$0.1379 \,\mathrm{mol}/100 \,\mathrm{eV}$	Ġн	$0.348 \,\mathrm{mol}/100 \,\mathrm{eV}$
$G_{CH_2}$	$1.9242 \,\mathrm{mol}/100 \,\mathrm{eV}$	$G_{\rm H_2}$	$1.924 \,\mathrm{mol}/100 \,\mathrm{eV}$
$G_{CH}$	$0.0648 \,\mathrm{mol}/100 \,\mathrm{eV}$	$G_{\Omega}$	3.8265 mol/100 eV

conditions of the experiment, can now be computed as indicated in Table 1.

The product distribution compared with the experimental results is as indicated in Fig. 4. As can be seen from Fig. 4, the calculated results do agree with the experimental results for the case of  $H_2$ , CO, CO<sub>2</sub>. Formation of  $C_2$  species, however could not be well explained. Terminations of the produced  $CH<sub>2</sub>$ , CH<sub>3</sub> species are probably the direct pathways for  $C<sub>2</sub>$ formation. The most likely occurrence of such interaction is in the local discharge volumes where the condition of the uniform mixing or well mixed situation is not valid. Nevertheless,  $C_2$ production, viz.  $C_2H_4$ , does not contribute substantially to the final product distribution. Hence, the obtained parameters can now be used for studying the chemical pathways and the significant reactions that can influence the product composition at a particular temperature.

#### *3.2.3. Calculation at higher power input*

For verification of the obtained parameters, the calculated results are compared with experimental results of Pietruszka and Heintze  $[6]$ , related to gas phase  $CH_4$  conversion in an empty DBD at 200  $\degree$ C at various CH<sub>4</sub>/O<sub>2</sub> ratios. Various energy definitions have been used to characterize conversion or removal of compounds in non-thermal plasma condition. For the case of CH4 conversion, the results in the present investigation are represented as kJ/mol CH4. Experimental data from the results of Pietruszka and Heintze [\[6\]](#page-10-0) are re-plotted as indicated in Fig. 5. The calculated results do agree with the experimental results for the case of low power consumption  $\left($ <1000 kJ/mol CH<sub>4</sub>). However, for the case of high energy input, the conversion of the input electrical energy into thermal energy becomes significant and induces additional conversion. From energy efficiency point of view, chemical conversion resulting from thermal energy derived from electrical source at lower temperature is not desirable. Fur-



Fig. 4. Comparison of calculated and experimental results.



Fig. 5. Comparison of calculated and experimental results [\[6\]](#page-10-0) at various energy input (the value in parenthesis indicate the  $CH_4/O_2$  ratio).

thermore, the objective of the present paper is to investigate the plasma initiated reactions; therefore thermal reactions are not accounted for. From Fig. 5, it is quite evident that the calculated parameters and the proposed kinetic reaction scheme is adequate enough to describe the plasma assisted partial oxidation process.

#### *3.2.4. Sensitivity analysis*

One of the objectives of partial oxidation process is to obtain synthesis gas. Non-thermal plasma is used in order to facilitate reactions at lower temperature. However, as seen from the above experimental results, the selectivity for  $H_2$  is low (<30%). A sensitivity analysis is attempted in order to determine its oxidation pathways. The above developed kinetic scheme serves as a basis for identifying the pathways which lead to increase or decrease of selectivity to  $H_2$  and CO. A linear sensitivity analysis could be used to identify these pathways [\[4\].](#page-10-0) Here each reaction rate constant is increased by a factor of 10 (results are included when rate constants are changed by a factor 10) and its influence on  $H_2$ and CO selectivity is analyzed. The present approach aims not to influence the radical production terms by the gas discharge itself, since these were estimated from experimental results. The results of the investigation is represented by a parameter *S*, defined as:

$$
S_j = \left(\frac{Y_j - Y_{j0}}{Y_{j0}}\right) \times 100\tag{4}
$$

where  $Y_i$  is the selectivity when the rate constant of the reaction "*j*" is increased by a factor 10 and  $Y_{i0}$  is the actual selectivity (when rate constant is not altered).

Thus, a positive value for *S*, would indicate an increase in corresponding selectivity, and vice versa. The results of the analysis are presented in Fig.  $6(a$  and b) for the case of  $H_2$  and CO, respectively. The following observations can be made from the results of the sensitivity analysis:

(1) As per the mechanism proposed in [Fig. 3,](#page-3-0) one of the pathways for  $H_2$  production results from  $CH_2O/CH_3OH$ oxidation. Formation of CH3O and its subsequent reactions lead to a decrease in  $H_2$  production. From the reactions listed in [Appendix A,](#page-7-0) it can be inferred that one of the pathways for CH3O formation is from the termination of the liquid products such as  $CH<sub>2</sub>O$  and  $CH<sub>3</sub>OH$ . Hence, a high density of O/H radicals should favor  $H_2$  production.

<span id="page-5-0"></span>

Fig. 6. Sensitivity analysis for: (a) CO and (b)  $H<sub>2</sub>$ .

- (2) A high concentration of OH radicals leads to a decrease in the  $H_2$  selectivity. This can be a direct result of third body reaction of H and OH to produce  $H_2O$ .
- (3) Although reaction no. 84 seems to influence  $H_2$  production significantly, from the mechanistic point of view, it cannot be clearly explained. Since the major contribution of this reaction is for regeneration of  $CH_4$  and  $O_2$ , which re-initiates the partial oxidation process.
- (4) A general conclusion related to factors affecting decrease in CO production is the termination of  $CH<sub>3</sub>$  radicals. This is quite evident from the sensitivity exhibited towards reactions 36, 69, 141. An increased production of  $CH<sub>3</sub>$  (reaction 69) is accompanied by its termination to  $CH<sub>4</sub>$  via reaction 69 and further termination via reaction 141 to  $C_3$ formation.

Overall, the mechanism proposed in [Fig. 3,](#page-3-0) is valid for predicting/explaining the product spectrum for the case of partial oxidation process at the experimental conditions. In both cases (Fig. 6(a and b)), the pathways for  $H_2$  and CO formation is via the oxidation of the intermediate  $C_1$  oxygenates. Recent studies [\[11\]](#page-10-0) with in situ FTIR spectroscopy, during non-thermal plasma assisted methane oxidative conversion, have as well indicated the presence of oxygenates as an intermediate product at stoichiometric (CH<sub>4</sub>/O<sub>2</sub> = 1.8–2) compositions. However, the termination reactions for both cases (Fig. 6(a and b)) differ considerably. For the case of  $H_2$  formation, the termination of liquid products to  $CH<sub>3</sub>O$  limits  $H<sub>2</sub>$  selectivity, while for CO, the termination of the dissociated fragments  $CH<sub>3</sub>$ ,  $CH<sub>2</sub>$ , etc., acts as a limiting reaction.

#### **4. Combined partial oxidation and steam reforming**

An alternative method to increase  $H_2$  production is by combined partial oxidation and steam reforming. In the conventional thermal or catalytic process, the intention to combine these two distinctive approaches would be to utilize the heat liberated from the partial oxidation/combustion of methane for the endothermic reforming process. In a non-thermal plasma assisted process, the objective is to split water molecules either by energetic electron molecule collisions processes or by the radical reactions initiated by the methane partial oxidation process. However, experiments in the presence of steam did not result in significant change in the product distribution or in the conversion of  $CH<sub>4</sub>$  at similar experimental conditions ( $T < 200$  °C,  $E < 200$  kJ/mol CH<sub>4</sub>), except for the production of liquid phase products such as  $CH<sub>2</sub>O$ and CH3OH. A product distribution in presence of steam during partial oxidation of  $CH<sub>4</sub>$  is indicated in [Fig. 7.](#page-6-0) The results

<span id="page-6-0"></span>

Fig. 7. Product distribution seen at different energy input for the case of  $CH<sub>4</sub>/O<sub>2</sub> = 2$ .

indicate a higher selectivity towards formation of oxygenates at lower energy density  $(E < 100 \text{ kJ/mol CH}_4)$ . With an increase in energy input, the selectivity towards oxygenates decreases. In order to elucidate the mechanism of formation of liquid oxygenates, an in situ investigation is needed. Isotopes have been frequently employed in mechanistic investigations in order to trace the path of reactions. In this study,  $D_2O$  is used in order to identify steam conversion pathways or the role of steam in the mixed gas system  $(CH<sub>4</sub>/O<sub>2</sub>/\text{steam})$  in non-thermal plasma.

Dissociation of molecules in non-thermal plasma is related to the gas composition. As can be seen from the calculated results in the earlier section and as well as from other works [\[2,3,8\], n](#page-10-0)ot only gas composition but also the nature of the gas components influence the radical production process.

For the mechanistic investigation, experiments were done for the following cases:

- (a) pure steam reforming;
- (b) combined partial oxidation and reforming.

 $D_2$ O was used to generate steam and the resulting product distribution was analyzed by means of GC (TCD and FID) and a mass spectrometer (QMS). The temperature was kept constant as in the earlier experiments at 130 ◦C and at a constant power input of  $2.5 \text{ kW}$  or  $100 \text{ kJ/mol}$  CH<sub>4</sub>.

Fig. 8(a and b) indicates the relative contribution to  $H_2$  formation from steam and CH4 at various temperature (130 and 200 °C) and CH<sub>4</sub>/O<sub>2</sub> ratio. D<sub>2</sub>O was used to generate steam.  $H_2$ , HD and  $D_2$  was particularly studied since  $H_2$  would be one of the product formed resulting from steam conversion. An obvious conclusion from the observed results is that in presence of O2, steam conversion is almost negligible. Results indicate that in presence of  $O_2$ , dissociation of water molecules by plasma is almost negligible. Perhaps the only contribution is to act as a carrier for the intermediates formed during the conversion process. In other words, it acts as a quenching media for the partial oxidation process. The problem then is not related to reaction kinetics, but mass transfer of the produced oxygenates in order to quench the reaction. This can perhaps explain the observed liquid products observed during the conversion



Fig. 8. Relative contribution to  $H_2$  formation from steam and CH<sub>4</sub> at varying temperature: (a)  $T = 130 °C$ ,  $E = 71$  kJ/mol CH<sub>4</sub> and (b)  $T = 200 °C$ ,  $E = 71$  kJ/mol CH<sub>4</sub>.

process (Fig. 7). A further analysis of the results in Fig. 7 would also indicate the confirmation of the reaction pathways indicated in [Fig. 3.](#page-3-0) At lower energy inputs, liquid oxygenate production is higher, which further dissociates as energy input is increased. Thus, quenching the reaction can lead to higher oxygenates production. Similar results related to liquid oxygenates production has been reported [\[12\],](#page-10-0) where, instead of steam, cooled electrode walls and micro gaps have been used in order to quench the reaction, and therefore avoid further gas phase oxidation.

Based on the above analysis, further work would focus on incorporating the "right" catalytic surface in order to control the product formation. From the available results, with the present configuration, only stable molecules or intermediates formed during the course of gas phase reaction have sufficient lifetime to interact/react at the surface. Alternative reactor design or electrode design can be incorporated in order to generate plasma on the surface so as to decrease mass transfer limitation [\[3\].](#page-10-0) This will be part of the further work.

#### **5. Summary and conclusion**

The following observations could be drawn from the analysis presented in the present paper:

- <span id="page-7-0"></span>(1) Plasma assisted CH4 partial oxidation process at a ratio of 2–4 proceeds mainly via oxygenate formation.
- (2) Excess oxidation of  $H_2$  is one of the limiting reactions for increasing  $H_2$  production/selectivity at the experimental conditions. For the case of CO, the termination reaction of the dissociated fragments acts as a limiting reaction.
- (3) In the presence of  $O_2$ , steam conversion is almost negligible at the experimental conditions. The main role is to quench the reaction or otherwise to separate the stable intermediates formed during the course of the reaction.

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### **Appendix A**

Reactions and the rate constants (rate constants are obtained from: <http://kinetics.nist.gov/chemistry>)



# Appendix A (*Continued* )



# Appendix A (*Continued* )



<span id="page-10-0"></span>



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